

Title (en)

Equipment for treating gases and use of said equipment for treating a synthesis gas contaminated with tars

Title (de)

Einrichtung zur Behandlung von Gasen und Verwendung der besagten Einrichtung zur Behandlung eines mit Teeren verschmutzten Synthesegases

Title (fr)

Équipement pour le traitement de gaz et utilisation dudit équipement pour traiter un gaz de synthèse contaminé par des goudrons

Publication

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Application

**EP 12382295 A 20120724**

Priority

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Abstract (en)

The present invention relates to a system provided with two chambers, one treatment chamber (1) and another heating chamber (14), for treating gases by means of thermal plasma technology. Separating both chambers is an intermediate wall (4) such that the gas under treatment does not come into direct contact with the plasma, thus preventing a dilution of the combustible gases, which would cause a loss of their calorific value and a contamination of their composition.

IPC 8 full level

**C10K 3/00** (2006.01); **C10J 3/00** (2006.01); **H01L 21/02** (2006.01)

CPC (source: EP)

**C10J 3/00** (2013.01); **C10K 3/003** (2013.01)

Citation (applicant)

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